

Day : Thursday
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Inventor Name Search Result

Your Search was:

Last Name = HAMAMURA

First Name = YUICHI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 12
<u>10296887</u>	Not Issued	030	11/29/2002	PROBE DRIVING METHOD, AND PROBE APPARATUS	HAMAMURA, YUICHI
<u>10269411</u>	Not Issued	030	10/10/2002	METHOD OF TESTING ELECTRONIC DEVICES	HAMAMURA, YUICHI
<u>10269268</u>	Not Issued	030	10/10/2002	PHOTOMASK FOR TEST WAFERS	HAMAMURA, YUICHI
<u>10269199</u>	Not Issued	030	10/10/2002	SYSTEM FOR TESTING ELECTRONIC DEVICES	HAMAMURA, YUICHI
<u>10269127</u>	Not Issued	030	10/10/2002	METHOD FOR TEST CONDITIONS	HAMAMURA, YUICHI
<u>10126263</u>	Not Issued	071	04/19/2002	METHOD OF MANUFACTURING ELECTRONIC DEVICES	HAMAMURA, YUICHI
<u>09783604</u>	Not Issued	030	02/15/2001	A METHOD AND SYSTEM FOR ANALYZING CIRCUIT PATTERN DEFECTS	HAMAMURA, YUICHI
<u>09417996</u>	<u>6344115</u>	150	10/13/1999	PATTERN FORMING METHOD USING CHARGED PARTICLE BEAM PROCESS AND CHARGED PARTICLE BEAM PROCESSING SYSTEM	HAMAMURA , YUICHI
<u>09311268</u>	<u>6476387</u>	150	05/14/1999	METHOD AND APPARATUS FOR OBSERVING OR PROCESSING AND ANALYZING USING A CHARGED BEAM	HAMAMURA , YUICHI
<u>09195711</u>	<u>6303932</u>	150	11/19/1998	METHOD AND ITS APPARATUS FOR DETECTING A SECONDARY ELECTRON BEAM IMAGE AND A METHOD AND ITS APPARATUS FOR	HAMAMURA , YUICHI

				PROCESSING BY USING FOCUSED CHARGED PARTICLE BEAM	
<u>08844433</u>	<u>5952658</u>	150	04/18/1997	METHOD AND SYSTEM FOR JUDGING MILLING END POINT FOR USE IN CHARGED PARTICLE BEAM MILLING SYSTEM	HAMAMURA , YUICHI
<u>08788421</u>	<u>5976328</u>	150	01/27/1997	PATTERN FORMING METHOD USING CHARGED PARTICLE BEAM PROCESS AND CHARGED PARTICLE BEAM PROCESSING SYSTEM	HAMAMURA , YUICHI

Inventor Search Completed: No Records to Display.

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